

## CONTENTS

### TURBOMOLECULAR PUMPS

|  |    |
|--|----|
| Mass Separation in a Turbomolecular Pump<br>T. Sawada .....  | 1  |
| New Developments in the Field of High Performance Turbo Molecular Pumps for the Production of Oil-Free High and Ultrahigh Vacuum<br>J. Henning ..... | 5  |
| On Performance Improvement of Axial-Flow Molecular Pump<br>S. Iida and O. Kimura .....   | 9  |
| A New Series of Turbomolecular Pumps<br>W. Bächler, R. Frank, and E. Usselmann .....   | 13 |
| Dynamic Seals<br>L. Maurice .....  | 17 |
| A New Molecular Pump<br>L. Maurice .....   | 21 |

### DIFFUSION AND MECHANICAL PUMPS

|  |       |
|--|-------|
| *Diffusion Pump Technology<br>M. H. Hablanian .....  | 25    |
| Characteristics of Single Structure Vapour Pumping Groups<br>B. D. Power, N. T. M. Dennis, R. D. Oswald, and B. H. Colwell ..... | 33    |
| Characteristics of a New Diffusion Pump Fluid<br>K. Sakuma and M. Nagayama .....   | 37    |
| Backstreaming in Diffusion Pump Systems<br>G. Rettinghaus and W. K. Huber.....   | A-853 |
| Oil Lubrication/Sealing on Mechanical Vacuum Pumps<br>D. B. Webb.....  | A-853 |

### GETTERS, GETTERING AND ION PUMPS

|  |    |
|--|----|
| Predicting and Evaluating Titanium Sublimation Pump Performance<br>D. J. Harra .....                       | 41 |
| Mercury Dispensing and Gettering in Fluorescent Lamps<br>P. della Porta and E. Rabusin .....               | 45 |
| Zirconium-Aluminium Alloy as a Getter for High Intensity Discharge Lamps<br>A. Barosi and E. Rabusin ..... | 49 |
| *Getters and Gettering<br>T. A. Giorgi .....   | 53 |

\* : Invited paper

|  |       |
|--|-------|
| Gettinger Rates of Hydrogen and Deuterium by Titanium and Elevated Temperature<br>M. Nagasaka and T. Yamashina ..... | 61    |
| Starting Characteristics of Triode and Diode Sputter-Ion Pumps<br>A. Konishi and S. Mizumachi .....                  | 65    |
| Theory of the Quadrupole Ion Pumps<br>H. Hora and H. Schwarz .....   | 69    |
| A New Modified Orbitron Pump<br>P. K. Naik and S. L. Verma .....   | 73    |
| Characteristics of Orbitron Pump<br>S. Kato, M. Nojiri, and H. Oikawa.....   | A-854 |

### CRYOPUMPS

|  |       |
|--|-------|
| The Optimisation of a Tubular Condensation Cryopump for Pressures Below $10^{-13}$ Torr<br>C. Benvenuti and D. Blechschmidt .....            | 77    |
| *Relations between Cryogenics and Vacuum Technology up to Now and in the Future<br>G. Klipping .....   | 81    |
| Some Considerations on Large-Sized Catalytic Pumps for Nuclear Fusion Apparatus<br>Y. Murakami, T. Kurisaki, Y. Ishibe, and K. Okamoto ..... | 89    |
| A New Cryosorption Pump for Better Ultimate Vacua<br>C. V. G. Nair and P. Vijendran .....  | 93    |
| Cryosorption Pumping at 77°K from Atmospheric Pressure to $10^{-7}$ Torr<br>R. Dobrozemsky and G. Moraw .....                                | 97    |
| Condensation Cryopump with Independent Cryogenerator<br>I. Blinow and V. Minaichev .....   | 101   |
| Cryosorption Pumping for Intersecting Storage Rings<br>H. J. Halama and J. R. Aggus.....   | A-854 |

### PRESSURE MEASUREMENT

|  |     |
|--|-----|
| Low Pressure Limitation of the Orbitron Ionization Gauge<br>D. Blechschmidt .....  | 105 |
| A Pulsed Discharge Vacuum Gauge<br>K. Kageyama, S. Monma, F. Fukazawa, and N. Kuriyama .....   | 109 |
| Relative Ion Gauge Sensitivities to Various Hydrocarbon Gases<br>K. Nakayama and H. Hojo .....   | 113 |
| *The Flow of Rarefied Gases in Vacuum Systems and Problems of Standardization of<br>Measuring Techniques<br>W. Steckelmacher .....   | 117 |
| A Comparative Study of the Metrological Characteristics of a Fixed and Variable<br>Conductance Dynamic System for Vacuum-Gauge Calibration<br>A. Calcatelli, C. Ferrero, G. Rumiano, and G. Ughi ..... | 127 |
| Standard Systems in Vacuum, and Development Trends<br>A. Calcatelli, C. Ferrero, G. Rumiano, and G. Ughi .....   | 131 |
| Pressure Measurement by the Brownian Motion. Absolute Measurement of Vacuum<br>Pressure Through the Spectral Analysis of Brownian Motion<br>M. Morimura, K. Nakagawa, and Y. Nezu .....                | 135 |

|   |     |
|---|-----|
| Accuracy of ( $\Delta p/p$ ) = $10^{-7}$ Obtained on a Differential Interferometric Manometer MDI<br>Used with Recorder | 139 |
| J. L. Truffier and P. S. Choumoff .....   | 139 |
| High Pressure Ionization Gauge for Calibration in the $10^{-7}$ to $10^{-1}$ Torr Range                                 |     |
| P. S. Choumoff and B. Iapteff .....   | 143 |
| The McLeod Gauge (1874-1974)-Its Birth-Its Development-Its Actuality  |     |
| E. Thomas and R. Leyniers .....   | 147 |
| Observations and Measurement of the Mercury Pumping Effect on Several Gases by Four<br>New Methods                      |     |
| L. B. Thomas, R. E. Harris, and C. L. Krueger .....   | 151 |
| A Monte Carlo Study of the 3-Gauge Pumping Speed Test Dome  |     |
| D. R. Denison .....   | 155 |

## PARTIAL PRESSURE MEASUREMENT AND MASS ANALYSIS

|   |       |
|---|-------|
| Mass Spectrometry Applied to Human Breath Analysis  |       |
| P. J. Bryant, O. H. Weddle, and P. L. Gutshall .....  | 159   |
| Precision and Accuracy of Mass Spectrometer Analysis in the Direct Gas Inlet System<br>(fundamental consideration for respiratory gas analysis) |       |
| I. Niishi, S. Sugai, and K. Kimura .....  | 163   |
| A High Sensitivity Programmable Mass Spectrometer   |       |
| F. Nakao and T. Yamamoto .....  | 167   |
| An Improved Method for Measurements of Very Low Partial Pressures   |       |
| H. Miyake and M. Michijima .....  | 171   |
| Optimization of the Adjustments of a Quadrupole Mass Spectrometer for the Analysis<br>of Gases in Metals  |       |
| J.-M. Welter.....   | 175   |
| A New Approach to the Implementation of a Delayed DC Ramp Quadrupole Mass Filter  |       |
| W. M. Brubaker .....  | 179   |
| A New Digitally Controlled, Computer Compatible Quadrupole Mass Spectrometer  |       |
| H. Egli, W. K. Huber H. Selhofer, and R. Vogelsang .....  | A-855 |
| A Peak Sharpener for Magnetic Mass Spectrometers  |       |
| W. M. Brubaker.....   | A-855 |

## PARTICLE ACCELERATORS

|  |     |
|--|-----|
| *Superconductivity, Cryogenics, and Vacuum Technology for Linear Accelerators                        |     |
| E. L. Garwin .....   | 183 |
| Pulsed Gas Shutter   |     |
| H. Ishimaru, S. Fukumoto, and N. Yagi .....  | 191 |
| A Vacuum System for a 30 MV Tandem van de Graaff   |     |
| B. S. Halliday .....   | 195 |
| *Vacuum and Ultrahigh Vacuum for Particle Accelerators and Storage Rings                             |     |
| E. Fischer .....   | 199 |
| A Scheme of Initial Start of a Large Vacuum System with Sputter Ion Pump without<br>Baking Procedure |     |
| G. Horikoshi, K. Satoh, and H. Mizuno .....  | 205 |

|  |     |
|--|-----|
| The UHV-System for the DESY Electron-Positron Double Storage Ring "Doris"  |     |
| Ch. Falland, H. Goedecke, H. Hartwig, J. Kouptsidis, H-Ch. Lewin, H. Münster,<br>H. Pingel, G. Schumann, and M. Schwartz ..... | 209 |

### NUCLEAR FUSION

|   |     |
|---|-----|
| The Vacuum Chamber of a TOKAMAK Plasma Experiment (TFR)                               |     |
| Z. Sledzieski, M. Huguet, P. H. Rebut, and A. Torossian .....                         | 217 |
| Vacuum Problems Associated with the Conceptional Design of TOKAMAK Fusion<br>Reactors |     |
| G. Lewin and F. H. Tenney .....   | 221 |
| *Vacuum Problems in Plasma Physics and Controlled Nuclear Fusion                      |     |
| F. Prévot .....   | 225 |
| *The Vacuum Technique of Nuclear-Fusion Installations                                 |     |
| Yu. M. Pustovoit .....  | 233 |

### VACUUM SYSTEMS AND APPLICATIONS

|  |     |
|--|-----|
| *Vacuum Industry in Japan  |     |
| C. Hayashi .....   | 241 |
| A New Vacuum System for an Electron Microscope   |     |
| N. Yoshimura, S. Ohmori, Y. Nagahama, and H. Oikawa .....  | 249 |
| A New Cold Sputtering System Using a Trapping Electrode  |     |
| S. Aoshima and T. Asamaki .....  | 253 |
| Applicability and Limits of Automatic Leak Detection below $10^{-8}$ Torr · liter/s  |     |
| U. Beeck and G. Reich .....  | 257 |
| Attainment of Outgassing Rates below $10^{-13}$ Torr · liters/sec $\text{cm}^2$ for Aluminum and<br>Stainless Steel After Bakeout at Moderate Temperatures |     |
| G. Moraw and R. Dobrozemsky .....  | 261 |
| Electric Discharge Ablation of Plastics in Vacuum  |     |
| M. Hirata and K. Nakayama .....  | 265 |

### SURFACE PHENOMENA (I)

|   |     |
|---|-----|
| *Interaction of Light Ions with Surfaces  |     |
| G. M. McCracken .....   | 269 |
| Electron Emission from Vacuum Evaporated Tin-Oxide Films  |     |
| T. Hanasaka, T. Satake, M. Hashiba, and T. Yamashina .....  | 277 |
| Thin Film Cathode of Lanthanum Hexaboride ( $\text{LaB}_6$ )                                      |     |
| C. Oshima, S. Horiuchi, and S. Kawai .....  | 281 |
| Surface Condition and Thermionic Emission of $\text{LaB}_6$                                       |     |
| S. Hosoki, S. Yamamoto, K. Hayakawa, and H. Okano .....   | 285 |
| Field Emission Studies of TiC Single Crystal  |     |
| K. Senzaki and Y. Kumashiro .....   | 289 |
| A Novel Evaluation Method of Rapidly Varying Work Function Values in Field Emission<br>Microscopy |     |
| R. R. Maly .....  | 293 |

## SURFACE PHENOMENA (II)

|  |     |
|--|-----|
| *Adhesion, Friction, Wear and Lubrication in Vacuum<br>D. H. Buckley .....   | 297 |
| Frictional Behavior of Molybdenum Disulfide in High Vacuum<br>M. Matsunaga and K. Hoshimoto .....  | 305 |
| Concentration Change of Sn in the Surface Layers of Cu-Sn Alloy System Due to Friction<br>K. Nakajima, A. Isogai, and Y. Taga .....  | 309 |
| Microadhesion between Hard Solids Caused by Very Light Loads<br>A. Kohno and S. Hyodo .....  | 313 |
| *The Relationship of Solid Surfaces to Vacuum Science and Technology<br>J. P. Hobson .....   | 317 |
| Adsorption Studies of Oil Molecules on Borosilicate Glass Surface Using Molecular Beam Techniques<br>K. Shimada, M. Kobayashi, and G. Tominaga .....                               | 327 |
| Simultaneous Adsorption of Nitrogen and Mercury on a Pyrex Glass Surface<br>M. Kobayashi, Y. Tuzi, and K. Asao .....   | 331 |
| Measurement of Thermal Accommodation Coefficients of Noble Gases on Tungsten with Different Surface Structures between 300 and 370K<br>J. Bierhals, G. Grosse, and G. Messer ..... | 335 |
| Surface Studies of Sintered and Single Crystal UO <sub>2</sub> by Low Energy Ion Bombardment<br>A. Cavalera and F. Vasiliu .....   | 339 |

## SURFACE ANALYSIS

|   |       |
|---|-------|
| A High Resolution Electron Spectrometer for Auger-Electron-Spectroscopy (AES)<br>H. G. Nöller, H. D. Polaschegg, and H. Schillalies .....   | 343   |
| Analysis of Chromate Conversion Coatings on Aluminum<br>R. J. Sunderland .....  | 347   |
| Surface and Grain Boundary Segregation of Steel Impurities<br>H. Shimizu, M. Ono, K. Nakayama, and M. Yamada .....  | 351   |
| Field-Ion Microscope Observations of Sputtered Tungsten Surfaces<br>J. M. Walls, E. Braun, and H. N. Southworth .....   | 355   |
| Instrumental Problems of Electron Microprobe Auger Spectroscopy<br>M. Ono, H. Shimizu, and K. Nakayama .....  | 359   |
| Composition Profiles of Several Contaminated and Cleaned Surfaces of Gold Thick Films on Copper Plates by Auger Electron and Secondary Ion Mass Spectroscopies<br>S. Komiya, M. Mizuno, T. Narusawa, H. Maeda, and M. Yoshikawa ..... | 363   |
| Absolute Atomic Densities Determined by Auger Electron Spectroscopy<br>P. Staib and J. Kirschner.....   | A-856 |

## ION MICROPROBE ANALYSIS

|  |     |
|--|-----|
| *Secondary Ion Mass Spectrometry and Its Application in Thin Film and Surface Layer Research<br>H. W. Werner ..... | 367 |
|--|-----|

|  |     |
|--|-----|
| Surface Observation of Insulating Materials with Ion Microprobe Analyzer<br>K. Nakamura, A. Shibata, K. Kondo, and H. Tamura .....               | 375 |
| In Depth Analysis in Selected Area with Ion Microprobe Analyzer<br>H. Tamura, T. Kondo, I. Kanomata, K. Nakamura, and Y. Nakajima .....          | 379 |
| Result on a UHV-Ion Microprobe for Surface and Trace Analysis<br>F. G. Rüdenauer and W. Steiger .....  | 383 |
| Ion Microprobe Mass Analysis for Iron and Steel Research<br>R. Matsumoto, K. Sato, and K. Suzuki .....   | 387 |
| Application of the Ion Microprobe Mass Analyzer to Problems in Steels<br>K. Tsuruoka, K. Tsunoyama, Y. Oohashi, and T. Suzuki .....              | 391 |
| On Improvements of the Measurement Accuracy in Diffusion Profiles of Doped Elements in Semiconductors by IMMA<br>K. Nagai and M. Yamaguchi ..... | 395 |
| Isotope Analysis in Iron Meteorites with Ion Probe Mass Spectrometer<br>H. Nishimura and J. Okano .....  | 399 |

## ION TECHNOLOGY

|   |     |
|---|-----|
| *Multiple Ionization by Sequential Electron Impact<br>P. A. Redhead .....   | 403 |
| Design and Operating Characteristics of a Low Pressure Ion Source<br>R. K. Fitch, A. M. Ghander, G. J. Rushton, and R. Singh .....  | 411 |
| Production and Measurement of Dense Metal Ions for Physical Vapor Deposition by a Hollow Cathode Discharge<br>S. Komiya and K. Tsuruoka.....                                      | 415 |
| A Trapped Ion Source with Improved Ionizing Efficiency for the Production of Multiply Charged Ions<br>C. P. Gopalaraman.....  | 419 |
| Beam-Plasma Type Ion Source for High-Intensity Ion Beam and Its Application to Surface Micro-Analyzer<br>T. Takagi, I. Yamada, J. Ishikawa, F. Sano, and T. Kishi .....           | 423 |
| Vapourized Metal Cluster Ion Source for Ion Plating<br>T. Takagi, I. Yamada, K. Yanagawa, M. Kunori, and S. Kobiyama .....  | 427 |
| Ion Milling by Beam Scanning Techniques—Effect of Beam Diameter on Milled Surface Shape<br>H. Yasuda .....  | 431 |
| RF Sputter-Etching by Fluoro-Chloro-Hydrocarbon Gases<br>N. Hosokawa, R. Matsuzaki, and T. Asamaki .....  | 435 |
| Interaction of Ion Beams with Polymer Surfaces Leading to Etching and Sputtering Processes<br>Ch. Weissmantel, M. Rost, O. Fiedler, H.-J. Erler, H. Giegengack, and J. Horn ..... | 439 |

## DEPOSITION AND PRODUCTION TECHNIQUES

|   |     |
|---|-----|
| *Recent Advances in Ion Plating<br>D. M. Mattox ..... | 443 |
|---|-----|

|   |       |
|---|-------|
| On the Application of Ion Plating Technique to Tribology<br>N. Ohmae, T. Nakai, and T. Tsukizoe .....   | 451   |
| Study of Deposition Process and Film Property in Ion Plating<br>K. Matsubara, Y. Enomoto, G. Yaguchi, M. Watanabe, and R. Yamazaki .....                    | 455   |
| Structures of Gold Thin Films Formed by Ion-Plating<br>Y. Murayama .....  | 459   |
| On the Influence of Oxygen and Water Vapour on the Reactive Condensation of Metal Oxides<br>K. O. J. Kerner .....   | 463   |
| Investigation of the Reaction of Compound Formation in the Reactive Evaporation Process<br>A. Itoh and S. Misawa .....                                      | 467   |
| Large Area Thin Films of Highly Uniform Thickness Vacuum Deposited in a Stationary System<br>H. J. Schwarz, R. C. McCord, and A. Nerken .....               | 471   |
| Production and Properties of Transparent Electroconductive Coating on Polyester Film<br>S. Sobajima, H. Okaniwa, N. Takagi, I. Sugiyama, and K. Chiba ..... | 475   |
| The Production of Conductive and Transparent Thin Films<br>G. Kienel and G. Gallus .....  | 479   |
| Multi-Channel Closed Loop Rate Monitor for Multiple Evaporation Sources<br>J. L. Terry and J. D. Michaelsen .....   | 483   |
| Thin-Film Tungsten for Silicon Integrated Circuit Applications<br>A. K. Sinha .....   | 487   |
| Preparation and Properties of Ultra Fine Metal Powders<br>S. Kashu, M. Nagase, C. Hayashi, R. Uyeda, N. Wada, and A. Tasaki .....                           | 491   |
| Inorganic Thin Film by Glow Discharge Technique<br>K. Horiguchi, A. Senda, and K. Kurata.....   | A-856 |
| Thin Film Metallization and Pattern Generation Techniques<br>A. Pfahnl.....   | A-857 |
| Theoretical Distribution of Deposited Film Thickness on Rotating Substrates<br>Y. Kawashimo.....  | A-857 |
| LiAl and LiIn Thin Films by "Sandwich-Type Evaporation Method"<br>H. Kezuka and K. Iwamura.....   | A-858 |

## SPUTTERING

|  |     |
|--|-----|
| *Sputtering in Thin Film Analysis Methods<br>G. K. Wehner .....  | 495 |
| A Study of the Neutral Species RF Sputtered from Oxide Targets<br>J. W. Coburn, E. Taglauer, and E. Kay .....  | 501 |
| Mass Spectrometric Analysis in RF Reactive Sputtering Discharge<br>F. Shinoki and A. Itoh .....  | 505 |
| New Developments in Ion Beam Sputtering and Etching Techniques<br>Ch. Weissmantel, O. Fiedler, G. Reisse, H.-J. Erler, J. Herberger, U. Scheit, and<br>M. Rost .....                               | 509 |
| The Effect of the Light Elements Nitrogen, Carbon and Oxygen on the Physical Properties<br>of Sputtered Tantalum Films<br>R. D. Huttemann, J. M. Morabito, C. A. Steidel, and D. Gerstenberg ..... | 513 |

|   |       |
|---|-------|
| Structure and Properties of $Cd_xHg_{1-x}Te$ Films<br>G. Cohen-Solal, C. Sella, D. Imhoff, and A. Zozime .....      | 517   |
| Film Resistors of Tubular Type Prepared by Asymmetric AC Sputtering<br>T. Mitsuoka, Y. Onodera, and T. Endo .....   | 521   |
| Mass Spectroscopy of Sputtered Neutrals and Its Application for Surface Analysis<br>H. Oechsner and W. Gerhard..... | A-858 |
| Production of Thin Oxides Films by Sputtering in a Ring Discharge<br>M. Hecq and J. Van Cakenberghe.....            | A-859 |

## FILM GROWTH

|  |     |
|--|-----|
| * <i>In Situ</i> Electron Microscopy of Thin Film Growth<br>J. F. Póczka, A. Barna, P. B. Barna, I. Pozsgai, and G. Radnóczki .....        | 525 |
| <i>In Situ</i> Electron Microscopy of Thin Film Growth on Clean Substrate in Clean Vacuum  |     |
| I. Technique   |     |
| K. Takayanagi, K. Yagi, K. Kobayashi, and G. Honjo .....   | 533 |
| II. Applications   |     |
| G. Honjo, K. Takayanagi, K. Kobayashi, and K. Yagi .....   | 537 |
| An UHV Evaporator for Thin Film Growth Study<br>G. Tominaga, C. Hayashi, K. Takeuchi, G. Shinohara, and K. Kinoshita .....                 | 541 |
| *Recent Developments in the Theory of Thin Film Condensation<br>G. Zinsmeister .....   | 545 |
| *Dependence of Growth and Physical Properties of Films on the State of the Substrate<br>O. S. Heavens .....                                | 551 |
| Evidence of the Effect of Nucleus Spatial Distributions on Thin Film Growth Kinetics<br>J. L. Robins, A. J. Donohoe, and B. F. Usher ..... | 559 |
| Heterogeneous Nucleation and Growth of Gold on Substrates<br>R. Anton, M. Harsdorff, M. Paunov, and H. Schmeisser .....                    | 563 |
| Growth Mode Discrimination of Thin Films by Auger Electron Spectroscopy<br>Y. Matsushita, K. Yagi, T. Narusawa, and G. Honjo .....         | 567 |
| Surface Diffusion Distances of Bismuth Adatoms on Mica Surface<br>H. Terajima and S. Fujiwara .....  | 571 |
| Stress in Epitaxed and Randomly Oriented Films of Ag, Cu and Au on Mica<br>Y. Nakajima and K. Kinoshita .....                              | 575 |
| Internal Stress and Growth of Gold Evaporated Films in U.H.V.<br>F. Shoji and S. Nagata .....  | 579 |
| *The Significance of Certain Crystal Parameters in Epitaxial Growth<br>J. H. van der Merwe and F. D. Auret .....                           | 583 |
| Growth of Au Film on GaAs (110) Observed by LEED and AES<br>K. Takeda, T. Hanawa, and T. Shimojo .....                                     | 589 |
| LEED Study of the Growth of Silver Film on GaP Surface<br>N. Miyata and T. Hanawa .....  | 593 |
| Geometric Factors Influencing Epitaxy in the Nickel-Silver and Silver-Nickel Systems<br>H. Jaeger and R. G. Sherwood .....                 | 597 |

|   |       |
|---|-------|
| Crystallinity and Epitaxy of Evaporated Germanium Films on Sodium Chloride Substrates<br>S. C. Chang and G. Shimaoka .....  | 601   |
| Electronmicroscopical Studies of UO <sub>2</sub> Thin Films Evaporated on NaCl Substrates with<br>Colloidal Contres<br>F. Vasiliu, V. Topa, N. G. Popescu-Pogrion, and M. I. Birjega..... | 605   |
| Homoepitaxial Growth of Silicon Films by Ion Sputtering<br>L. N. Aleksandrov and R. N. Lovyagin .....   | 609   |
| Epitaxial Deposition of Niobium Nitride by Sputtering<br>S. Kosaka and Y. Onodera .....   | 613   |
| *Brownian Motion of Crystallites on a Surface in Its Relation to Epitaxy<br>A. Masson.....  | A-859 |
| Nucleus Growth Rate of Vacuum-Deposited Thin Films<br>S. Fujiwara, H. Terajima, and S. Ozawa.....   | A-860 |
| LEED-AES Study on Clean (001) Iron Surface<br>T. Kanaji, J. Mameda, and S. Nagata.....  | A-860 |

### **DIFFUSION AND PHASE TRANSITION**

|   |       |
|---|-------|
| Misfit Dislocation Energy in a Crystal with Lattice Parameter Gradient<br>G. G. Cillié and J. H. van der Merwe.....   | 617   |
| Interdiffusion in Ni/Au and Ni-Fe/Au Thin Film Diffusion Couples<br>A. Gangulee .....   | 621   |
| Electromigration and Diffusion in Ni-Fe Thin Films<br>A. Gangulee and F. M. d'Heurle .....  | 625   |
| Critical Thickness for Loss of Coherency in Epitaxial Bimetals<br>K. Shinohara and J. P. Hirth .....  | 629   |
| Room Temperature Interaction in Bimetallic Thin Film Couples<br>K. N. Tu and R. Rosenberg .....   | 633   |
| Ion Backscattering Analysis of Mixing in Au-Cu and Au-Al Thin Films<br>S. U. Campisano, G. Foti, F. Grasso, and E. Rimini .....   | 637   |
| Electrotransport of Sn-Rich Liquid Zones in Thin Metal Films<br>J. K. Howard .....  | 641   |
| Recovery Process and Metastable Crystals in Vacuum Co-Deposited Mn-Al Films<br>K. Yoshida, S. Kawaguchi, and S. Nagata .....  | 645   |
| Change in Electrical Resistivity during Amorphous-Crystalline Phase Transition of<br>Antimony Films<br>K. Maki .....  | 649   |
| Study of Phase Transformation of Titanium in the Form of Needles and Evaporated Films<br>Using a Field Emission Microscope<br>D. Ramanathan, N. Venkatramani, and P. Vijendran .....                | 653   |
| Effect of Grain Boundaries and Local Variation Influence of Current Density and<br>Temperature on the Electromigration Damage in Gold Thin Films<br>J. C. Rouais, G. Lormand, and M. Chevreton..... | A-861 |

### **ANALYSIS OF FILMS**

|  |     |
|--|-----|
| *Mass Transport between Two Metal Layers as Studied by Ion Scattering<br>S. T. Picraux ..... | 657 |
|--|-----|

|  |       |
|--|-------|
| The Combination of SIMS and AES for the Analysis of Thin Films<br>R. Buhl, W. K. Huber, and E. Löbach .....  | 665   |
| Epitaxial Growth of Nickel Silicide NiSi <sub>2</sub> on Silicon<br>K. N. Tu, E. I. Alessandrini, W. K. Chu, H. Kraütle and J. W. Mayer .....              | 669   |
| Auger and Ellipsometric Study of Phosphorus Segregation in Oxidized Degenerate Silicon<br>N. J. Chou, Y. J. van der Meulen, R. Hammer, and J. Cahill ..... | A-861 |

### **OPTICAL FILMS AND OPTICAL PROPERTIES**

|   |       |
|---|-------|
| Analysis of Thin Films by Interferometric Ellipsometry<br>H. F. Hazebroek and A. A. Holscher .....  | 673   |
| Optical Effect of the Substrate on the Plasma Resonance Absorption of an Aggregated Silver Film<br>T. Yamaguchi and A. Kinbara .....                      | 677   |
| Optical Properties of RF Triode-Sputtered Thin Gold Films<br>R. Cornely and N. Fuschillo.....   | 681   |
| Variable and Gradient Refractive Index Multilayer Films of Different Materials<br>S. K. Sharma, V. N. Yadava, and K. L. Chopra .....                      | 685   |
| Measurements of Spectral Characteristics of Optical Thin-Film by Rapid Scanning Spectrophotometer<br>R. Hiraga, N. Sugawara, S. Ogura, and S. Amano ..... | 689   |
| Modern Instrumentation for the Optical Control of Thin Film Fabrication in High Vacuum<br>I. Wilmanns .....   | 693   |
| Fabrication of Lithium Niobate Light Guiding Films<br>L. M. Reiber, D. B. Ostrowsky, J. Y. Robic, and M. Papuchon .....                                   | 697   |
| Optical Characteristics of Corning 7059 Glass Films Deposited by RF Sputtering<br>Y. Shimamoto, H. Matsumaru, and T. Nishimura .....                      | 701   |
| Minimizing Interactions of Gases in Contaminating Thin Films during Charged Particle Bombardment<br>R. R. Brown .....                                     | 705   |
| *Plasma Oscillations in Metal Films<br>E. Kretschmann.....  | A-862 |
| Ultra-Microhardness of Some Vacuum-Deposited Films<br>M. Nishibori and K. Kinoshita.....  | A-862 |

### **ELECTRICAL PROPERTIES**

|  |     |
|--|-----|
| Nitrogen Doped Ta-Al Thin Films by DC Sputtering<br>J. Yamazaki, T. Kamo, and M. Nakamura .....  | 709 |
| Reactively Sputtered Platinum Oxide Films<br>W. D. Westwood and C. D. Bennewitz .....  | 713 |
| On the Switching Phenomena of Discontinuous Gold Films<br>S. K. Dey and G. D. Dick .....   | 717 |
| Electrical and Galvanomagnetic Properties of Bismuth-12 Atomic Percent Antimony Polycrystalline Thin Films<br>R. P. Agarwala V. C. George, and A. K. Dua ..... | 721 |

|  |       |
|--|-------|
| Utilization of Change in Barrier Height for Determination of the Energy-Momentum Relationship in Tunnel Junctions<br>K. H. Gundlach and J. Kadlec.....           | 725   |
| Electrical and Magnetic Properties of Pure Amorphous Cobalt Films<br>M. L. Kwan and R. W. Hoffman .....  | 729   |
| Investigation of Iron Films by Internal Conversion Electrons Emitted after the Mössbauer Excitation<br>T. Toriyama, M. Kigawa, M. Fujioka, and K. Hisatake ..... | 733   |
| Quantum Size Effect in Thin Bismuth Films and Their Structure<br>H. Asahi, T. Humoto, and A. Kawazu .....  | A-863 |
| Thermoelectric Voltage and Resistivity of Metallic Single Crystalline Thin Film Epitaxially Grown by Vacuum Deposition<br>T. Ota.....                            | A-863 |
| Aluminum Oxide Films Prepared by Electron Beam Evaporation of Sapphire<br>S. Okazaki, M. Kusaka, and M. Kanakura.....  | A-864 |
| Stress and Grain Structure of Magnetic Thin Films Related to the Perpendicular Anisotropy<br>H. Konno.....   | A-864 |

## DIELECTRIC FILMS

|  |     |
|--|-----|
| Physical Structure of DC Diode Sputtered ZnO Films and Its Influence on the Effective Electromechanical Coupling Factors<br>N. Chubachi, M. Minakata, and Y. Kikuchi ..... | 737 |
| Preferred Orientation in RF-Sputtered ZnO Films<br>H. W. Lehmann and R. Widmer .....   | 741 |
| Surface Wave Transducers of ZnO Films with Controlled Direction of C-Axis<br>K. Wasa, K. Ohji, O. Yamazaki, and S. Hayakawa .....  | 745 |
| Properties of LiNbO <sub>3</sub> Thin Films Fabricated by RF Sputtering<br>S. Fukunishi, A. Kawana, N. Uchida, and J. Noda .....   | 749 |
| Hydrophobic Conversion of the Chemical-Vapor-Deposited SiO <sub>2</sub> Surface<br>H. Yanazawa, H. Utsugi, N. Hashimoto, and M. Ashikawa .....                             | 753 |
| Water Adsorption on Chemically Vapor-Deposited Glass Films<br>E. Arai, Y. Terunuma, and C. Tadachi .....   | 757 |
| Optical Properties of Reactively-Evaporated Silicon Oxynitride Films<br>M. Mashita and K. Matsushima .....   | 761 |
| The Growth of Potassium Chloride Crystallites during the Evaporation in Argon Atmosphere<br>H. Washida and K. Kobayashi .....  | 765 |
| Properties of ZnS Films Evaporated in High Vacuum<br>A. Preisinger and H. K. Pulker .....  | 769 |

## SEMICONDUCTOR FILMS

|  |     |
|--|-----|
| *Impedance Measurements to Study Semiconductor Surface and Thin Insulating Films on its Surface<br>J. Nishizawa, M. Koyanagi, and M. Kimura..... | 773 |
|--|-----|

|   |       |
|---|-------|
| Thermal Conductivity of Amorphous vs. Crystalline Ge and GeTe Films<br>P. Nath and K. L. Chopra .....   | 781   |
| X-Ray Photoemission Study of Amorphous Tellurium<br>T. Ichikawa .....   | 785   |
| Preparation of High Mobility Tellurium Films<br>K. Okuyama and Y. Kumagai .....   | 789   |
| Mobility-Dependent Field-Effect Conduction of Vacuum-Deposited CdSe Layers<br>Y. Kumagai and K. Okuyama .....                                   | 793   |
| An Unusual Current Oscillation Phenomenon in CdSe Film Evaporated on Glass Substrate<br>S. K. Dey .....   | 797   |
| Investigations in Polycrystalline CdS-Films<br>R. Kassing and W. Bax .....  | 801   |
| HEED and EM Study of Obliquely Deposited Cadmium Telluride Films<br>N. G. Dhere, R. G. Pinheiro, and N. R. Parikh .....                         | 805   |
| Electroluminescence in ZnS: Mn <sub>x</sub> : Cu <sub>y</sub> RF-Sputtered Films<br>J. J. Hanak .....   | 809   |
| Switching and Negative Resistance Behavior of Ag/aSi/Ag Thin Film Structures<br>L. Mei and J. E. Greene .....                                   | 813   |
| Non-Linear Transport and Switching Properties of Transition Metal Oxides<br>N. Fuschillo and B. Lalevic .....                                   | 817   |
| The Properties of Thin Epitaxial PbTe Films Prepared under Very Clean and Closely Monitored Conditions<br>E. H. C. Parker and D. Williams ..... | A-865 |
| Pb <sub>x</sub> Sn <sub>1-x</sub> Te Layers by R.F. Multicathode Sputtering<br>C. Corsi .....   | A-865 |

## APPLICATIONS OF FILMS

|  |     |
|--|-----|
| *Computer Controlled Molecular Beam Epitaxy<br>L. Esaki .....  | 821 |
| Measurements of Local Lattice Strains Near Insulating Film Edges in Silicon Crystals<br>Y. Yukimoto and T. Hirao .....                           | 829 |
| Thin-Film Cryogenic Amplifier<br>G. Kramer .....   | 833 |
| Experimental Studies in Regard to an Electrostatic Thin Film Relay<br>R. Chabicosky and E. Sciri .....   | 837 |
| Relative Thermal Stabilities of Thin-Film Contacts to n-GaAs Metallized with W, Au and Pt<br>A. K. Sinha and J. M. Poate .....                   | 841 |
| Process in the Production of Multi-Layer Printed Circuits Using Vacuum Deposition<br>W. Fleischer, K. Petzold, H. Bollinger, and E. Göring ..... | 845 |
| On the Readhesion of Once Split Films<br>I. B. Yoon .....  | 849 |